FISCHERSCOPE® X-RAY XDV®-µ

X-Ray Fluorescence Measuring Instrument with a Polycapillary X-Ray Optics for Measurements on Very Small Components and Structures





FISCHERSCOPE® X-RAY XDV®-,

Description

The FISCHERSCOPE X-RAY XDV- μ is a universally applicable energy-dispersive x-ray measuring instrument. It is particularly well suited for non-destructive analyses and measurements of coating thicknesses on very small components and structures, even with complex coating systems.

Typical fields of application:

- Measurements on very small flat components and structures such as printed circuit boards, contacts or lead frames
- Analysis of very thin coatings, e.g., gold/palladium coatings of $\leq 0.1~\mu m$ (0.004 mils)
- Measurement of functional coatings in the electronics and semiconductor industries
- Determination of complex multi-coating systems
- Automated measurements, e.g., in quality control

To create ideal excitation conditions for every measurement, the instrument features electrically changeable primary filters. The modern silicon drift detector achieves high accuracy and good detection sensitivity. Due to the innovative polycapillary x-ray optics, the instrument measures using an extremely small measurement spot yet with a very high excitation intensity.

Outstanding accuracy and long-term stability are characteristics of all FISCHERSCOPE X-RAY systems. The necessity of recalibration is dramatically reduced, saving time and effort.

The fundamental parameter method by FISCHER allows for the analysis of solid specimens and coating systems without calibration.

For measurements on large printed circuit boards, the instrument can be equipped with a larger sample stage.

Design

The FISCHERSCOPE X-RAY XDV-µ is designed as a user-friendly bench-top instrument. It is equipped with a high-precision, programmable XY-stage and an electrically driven Z-axis. The housing features a slot in the side allowing for the measurement of even large components, e.g., pc-boards. The sample stage moves into the loading position automatically, when the protective hood is opened.

A laser pointer serves as a positioning aid and supports the quick alignment of the sample to be measured. A high-resolution color video camera simplifies the precise determination of the measurement spot.

The entire operation and evaluation of measurements as well as the clear presentation of measurement data is performed on a PC, using the powerful and user-friendly WinFTM® software.

The X-RAY XDV- μ instrument fulfills DIN ISO 3497 and ASTM B 568.

Intended use	Energy dispersive x-ray fluorescence measuring instrument (EDXRF) to measure thin		
-1	coatings and coating systems on very small flat structures		
Element range	Aluminum Al (13) to Uranium U (92) – up to 24 elements simultaneously		
Design	Bench-top unit with hood opening upwards and housing with a slot on the side X/Y- and Z-axis electrically driven and programmable Motor-driven changeable filters		
Measuring direction	Top down		
X-Ray Source/Detection			
X-ray tube	Standard: Micro focus tube with tungsten target and beryllium window Optional: Micro focus tube with molybdenum target and beryllium window		
High voltage	Three steps: 10 kV, 30 kV, 50 kV		
Primary filter	$4x$ changeable: Ni 10 μm (0.4 mils); free; Al 1000 μm (40 mils); Al 500 μm (20 mil		
X-ray optics	Polycapillary		
	Standard Non halo-free*	Option 20 µm Halo-free*	Option 10 µm Halo-free*
Measurement spot, fwhm at Mo-K _α	аррг. Ø 20 µm (0.8 mils)	appr. Ø 20 µm (0.8 mils)	appr. Ø 10 µm (0.4 mils
X-ray detector	Peltier-cooled silicon-drift-detector (SDD)		
Effective detector area	$20 \text{ mm}^2 (0.03 \text{ in}^2)$	50 mm² (0.08 in²)	50 mm² (0.08 in²)
Measuring distance between specimen surface to lower edge	fixed, approx. 4 – 5 mm (0.16 – 0.2 in)	fixed, approx. 4 – 5 mm (0.16 – 0.2 in)	fixed, approx. 1.5 – 2 mn (0.06 – 0.08 in)
of measuring head Video Microscope	* For halo-free capillaries, the concentrated on the nominal free, radiation intensity with harea than the nominal measures.	measurement spot. For capil nigh energies (E > 20 keV) co	laries, indicated as non hal
	High-resolution CCD color camera for optical monitoring of the measurement location along the primary beam axis, manual focusing and auto-focus, Crosshairs with a call brated scale (ruler) and spot-indicator, Adjustable LED illumination, Laser pointer (class 1) to support accurate specimen placement		
Zoom factor	Up to 1080x (Optical: 30x, 90x, 270x; Digital: 1x, 2x, 3x, 4x)		
Electrical data			
Power supply	AC 115 V or AC 230 V 50 / 60 Hz		
Power consumption	Max. 120 W		
Protection class	IP40		
Dimensions			

FISCHERSCOPE® X-RAY XDV®-µ

Approx. 135 kg (297 lb)

Width x depth x height: $660 \times 835 \times 720$ mm ($26 \times 33 \times 28.3$ in)

Width x depth x height: $580 \times 560 \times 145$ mm (22.8 x 22 x 5.7 in)

External dimensions

Interior dimensions of chamber

Weight

FISCHERSCOPE $^{\mathbb{R}}$ X-RAY XDV $^{\mathbb{R}}$ - μ

Sample Stage	Standard	Option Supporting Plate PCB		
	Fast, programmable XY-stage with	Fast, programmable XY-stage with pop-ou		
	pop-out function	function and large placement area for measurements on PCBs		
Usable sample placement area	Width x depth: 370 mm x 320 mm (14.6 in x 12.6 in)	Width x depth: 620 mm x 530 mm (24.4 in x 20.9 in)		
Usable maximum travel	X/Y-axis: 250 mm x 220 mm (9.8 in x 8.7 in)			
	Z-axis: 140 mm (5.5 in)			
Max. travel speed X/Y	60 mm/s (0.2 ft/s)			
Repeatability precision X/Y	direction-independent: $\leq 5~\mu m$ (0.2 mils) max., $\leq 2~\mu m$ (0.08 mils) typ.			
Max. sample weight	5 kg (11 lb), with reduced precision max. 20 kg (44 lb)			
Max. sample height	135 mm (5.3 in)			
Environmental Conditions				
Operating temperature	10 °C – 40 °C / 50 °F – 104 °F			
Storage/Transport temperature	0 °C – 50 °C / 32 °F – 122 °F			
Relative humidity	≤ 95 %			
Evaluation unit				
Computer	Windows [®] -PC with extension cards			
Software	Standard: Fischer WinFTM® BASIC includ	ing PDM [®]		
	Optional: Fischer WinFTM [®] SUPER			
Standards				
CE approval	EN 61010, EN 61326			
X-Ray standards	DIN ISO 3497 and ASTM B 568			
Approval	Individual acceptance inspection as a fully protected instrument according to the German regulations "Deutsche Röntgenverordnung-RöV".			
Order				
FISCHERSCOPE X-RAY XDV-µ	604-259			
Option 20 µm halo-free	605-404			
Option 10 µm halo-free	605-405			
Option Supporting Plate PCB	604-984			
	Special XDV product modification and XD	V technical consultation on request		
Sindelfingen - Germany.	are registered trademarks of Helmut Fischer Gr k of Microsoft Corporation in the United States a			

www.helmut-fischer.com



